# **Supporting Information**

## Mechanistic Understanding of Electrochemical Plating and Stripping of Metal

## Electrodes

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# Implementation of Transition events in the Mesoscale Kinetic Monte Carlo (KMC) Algorithm

Three processes that are included in the mesoscale Kinetic Monte Carlo (KMC) model during charging and discharging. Diffusion of metal ion in liquid electrolyte, diffusion of metal atom on the surface and reduction or oxidation for charging or discharging respectively. The probabilities for different processes are assigned to kinetic rates. A two dimensional lattice based KMC model is developed. A rejection free, partition search KMC algorithm is used<sup>1–3</sup>. The computational domain is periodic in horizontal direction. N<sub>x</sub> is the number of lattice points in the horizontal direction.

During charging, two set of matrices are maintained and updated. One is the occupancy matrix, which keeps track of the lattice sites that are occupied or empty. The other matrix is the charge matrix which keeps track whether an entity is a metal ion or a metal atom.

During discharging process, three set of matrices are maintained and updated. The occupancy and the charge matrix have the same definition as during the charging process. In addition, a connectivity matrix is created to keep track of metal atoms that are connected to the electrode and metal atoms that are disconnected to the substrate. A metal atom can be oxidized if it is connected to the electrode. Metal atoms not connected to the electrode are counted as dead metal.

For both charge and discharge process, the matrix containing the rate of all the processes is maintained and updated with each transition event.

The KMC algorithm involves the following steps.

#### Calculate the total rate

(i) The total rate for diffusion of Li ions in electrolyte

$$\Omega_{ion\_diffusion} = \sum_{i=1}^{N} R^{i}_{ion\_diffusion}$$
(S1)

(ii) The total rate for diffusion of Li atoms on surface

$$\Omega_{surface\_diffusion} = \sum_{i=1}^{N} R_{surface\_diffusion}^{i}$$
(S2)

(iii) Total rate of reduction or oxidation for charging or discharging

$$\Omega_{reduction / oxidation} = \sum_{i=1}^{N} R^{i}_{reduction / oxidation}$$
(S3)

N is the number of atoms and ions. Superscript i denotes the rate for a particular atom or an ion. The total rate is calculated as

$$\Omega_{total} = \Omega_{ion\_diffusion} + \Omega_{surface\_diffusion} + \Omega_{reduction / oxidation}$$
(S4)

#### Selection of the transition event

A partial search strategy is used to select the transition event. A random number  $\gamma_1$  uniformly distributed on (0,1) is generated. If  $0 < \gamma_1 \Omega_{total} \leq \Omega_{ion\_diffusion}$ , then ion diffusion is selected. If  $\Omega_{ion\_diffusion} < \gamma_1 \Omega_{total} \leq \Omega_{ion\_diffusion} + \Omega_{surface\_diffusion}$ , then surface diffusion is selected. If  $\Omega_{ion\_diffusion} + \Omega_{surface\_diffusion} + \Omega_{surface\_diffusion}$ , then reduction or oxidation is selected depending on whether it is charging or discharging. Figure S1 depicts this selection of the type of event schematically. In the example shown in Figure 2, diffusion of metal atom on surface is selected.

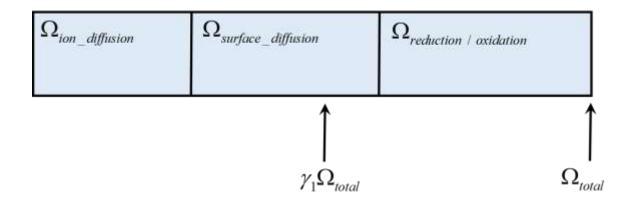


Figure S1: Schematic showing selection of type of the transition event.

The next step is to select the entity (specific ion or atom) for transition. In the example shown in Figure S1, surface diffusion is selected. Figure S3 shows schematically how to select the specific atom that will diffuse. Generate another random number  $\gamma_2$  uniformly distributed on (0, 1). Surface diffusion of the i<sup>th</sup> atom is enacted.

$$\sum_{j=1}^{i-1} R_{surface\_diffusion}^{j} < \gamma_2 \Omega_{surface\_diffusion} \le \sum_{j=1}^{i} R_{surface\_diffusion}^{j}$$
(S5)

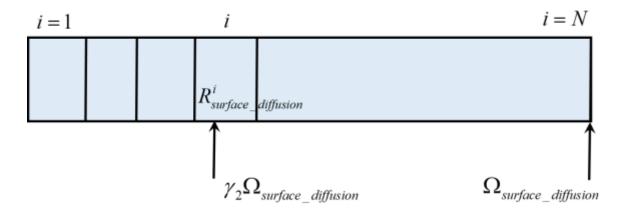


Figure S2: Schematic showing the selection of surface diffusion of the i<sup>th</sup> atom.

### Update structure and time

After the implementation of the transition event, the occupancy and the charge matrix is updated. The rate matrix is updated for the first and second neighbor of the entity (ion or atom) undergoing transition. If a reduction reaction occurs, another ion is introduced such that the number of ions in the KMC computational domain remains constant. Then the occupancy and charge matrix are modified to account for the additional ion. The matrix containing rates is also updated for the additional ion and its first and second neighbors. If an oxidation event occurs during discharging process, the occupancy and charge matrices are updated as well as the rates of first and second

neighbors of the atom that is oxidized. In addition, the connectivity matrix is updated to check if any new group of atoms have become detached from the electrode. Upon oxidation, an ion is removed from the computational domain so the number of ions remain constant throughout the discharge process. When an ion is removed, the occupation and charge matrices are updated. The rate of the first and second neighbor of the removed ion is also updated.

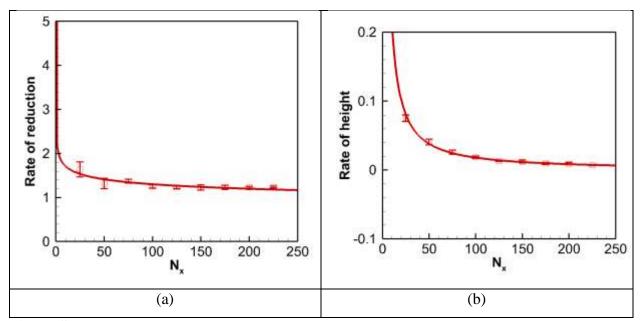
To update time, a random number,  $\gamma_3$  on (0, 1) is generated. The time increment  $\delta t$  is calculated as,

$\int_{\mathcal{S}_{t}} -\ln(\gamma_{3})$	(\$6)
$\partial t = \frac{1}{\Omega_{tot}}$	

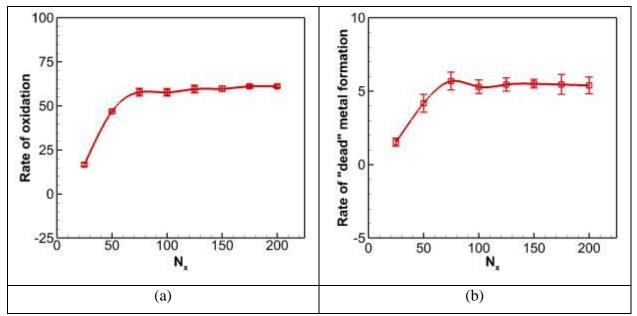
## **Computational Domain**

The two dimensional computational domain comprises of lattice grid of  $(N_x \times N_y)$  sites where N<sub>x</sub> is the number of lattice sites in horizontal direction and N<sub>y</sub> is the number of lattice sites in vertical direction. To study the effect of domain size, N<sub>y</sub>=100 is kept constant while N<sub>x</sub> is varied. Figure S3 shows the effect of domain size N<sub>x</sub> for charging. Rate of reduction is the average slope of the number of reduction reactions with time. Rate of height is the average slope of height of deposition with time. N<sub>x</sub>=175 is used in all KMC simulations based on the results shown in Figure S3.

Figure S4 shows the effect of computational domain during discharging. In Figure S4 (a), the rate of oxidation is the average slope of number of oxidation reactions with time and in Figure S4 (b), the rate of dead metal formation is the average slope of the number of dead metal with time.  $N_x$ =175 is used in all KMC simulations.



**Figure S3**: Effect of the KMC domain size during charging. (a) Rate of reduction as the number of lattice points in horizontal direction,  $N_x$  is increased (b) Rate of height of deposition with  $N_x$ . The KMC simulations were performed at  $P_{red}=0.1$ ,  $P_e=0.8$  and  $P_f=0.1$ .



**Figure S4:** Effect of the KMC domain size during discharging. (a) Rate of oxidation as the number of lattice points in horizontal direction,  $N_x$  is increased (b) Rate of dead metal formation with  $N_x$ . The KMC simulations were performed at  $P_{ox}=0.5$ ,  $P_e=0.4$  and  $P_f=0.1$ .

## References

- (1) Schulze, T. P. Efficient Kinetic Monte Carlo Simulation. J. Comput. Phys. 2008, 227 (4), 2455–2462.
- (2) Tewari, D.; Liu, Z.; Balbuena, P. B.; Mukherjee, P. P. Mesoscale Understanding of Lithium Electrodeposition for Intercalation Electrodes. *J. Phys. Chem. C* **2018**, *122*, 21097–21107.
- (3) Voter, A. F. Introduction To the Kinetic Monte Carlo Method. In *Radiation Effects in Solids*; 2011; pp 1–23.